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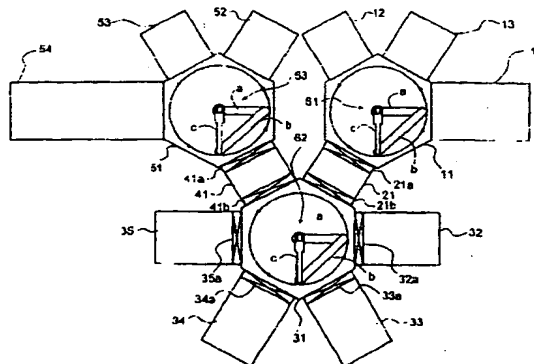
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(54) **System and process for fabricating an organic electro-luminescent display device**

(57) The invention provides an organic EL display device fabrication system comprising a loading side normal-pressure delivery chamber 11 including a first substrate delivery means 61 for delivering a substrate with no film formed thereon, and a loading chamber 21 connected thereto for introducing the substrate from loading side normal-pressure delivery chamber 11 at normal pressure into a vacuum delivery chamber 31 at a vacuum. The vacuum delivery chamber 31 is connected to loading chamber 21 and includes a second substrate delivery means 62 for delivering the substrate in a vacuum, and has one or two or more film formation chambers 32 to 35 connected thereto. The system further comprises an unloading chamber 41 connected thereto for delivering the substrate out of vacuum delivery chamber 31 at a vacuum into an unloading side normal-pressure delivery chamber 51 at normal pressure. The unloading side normal-pressure delivery chamber 51 is connected to unloading chamber 41 and includes a third substrate delivery means 63 for delivering a substrate with films formed thereon. An inert gas atmosphere having a moisture content of up to 100 ppm is maintained in both unloading chamber 41 and unloading side normal-pressure delivery chamber 51 at normal pressure. The invention also provides an organic EL display device fabrication process using this fabrication system.

FIG. 1



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EUROPEAN SEARCH REPORT

Application Number
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The present search report has been drawn up for all claims			
Place of search THE HAGUE		Date of completion of the search 10 September 2001	Examiner Drouot-Onillon, M-C
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